

(12)

Europäisches Patentamt
European Patent Office
Office europ 'en des brevets



Publication number:

0 552 561 A3

EUROPEAN PATENT APPLICATION

21) Application number: 92311671.9

22 Date of filing: 21.12.92

(int. Cl.⁶: **H01L 21/331**, H01L 21/20, H01L 29/161, H01L 29/73

Priority: 24.01.92 US 825524

Date of publication of application: 28.07.93 Bulletin 93/30

Designated Contracting States:
DE FR GB

Date of deferred publication of the search report: 02.08.95 Bulletin 95/31 Applicant: Hewlett-Packard Company 3000 Hanover Street Palo Alto, California 94304 (US)

2 Inventor: Turner, John E.
13660 Skyline Blvd.
Woodside, CA 94062 (US)
Inventor: Kamins, Theodore I.
4132 Thain Way
Palo Alto, CA 94306 (US)
Inventor: Scott, Martin P.
424 Clipper Street
San Francisco, CA 94114 (US)
Inventor: Keller, Yvonne H.
663 Hermitage Way
San Jose, CA 95134 (US)

Representative: Williams, John Francis et al WILLIAMS, POWELL & ASSOCIATES 34 Tavistock Street London WC2E 7PB (GB)

Method of fabricating an ultra-thin active region for high speed semiconductor devices.

(9) A method of fabricating a semiconductor device (10) to retard diffusion of a dopant from a center active region (14) into adjacent regions. The center active region is epitaxially formed by selectively increasing and decreasing an introduction of diffusion-suppressing material, preferably germanium, into a semiconductor material, preferably silicon, so that a vertical profile of the content of the diffusion-suppressing material is such that outdiffusion of a dopant is minimized. One embodiment of the tailoring is to increase the concentration of the diffusion-

suppressing material at both of the opposed sides of a base region of a bipolar transistor, thereby providing concentration peaks at the interfaces of the base region with collector (12) and emitter (14) regions. The concentration of germanium in a $\rm Si_{1-x} Ge_x$ layer is such that the value x is within the range 0.08 to 0.35 and optimally within the range 0.15 to 0.31. The dopant, preferably boron, also has a tailored concentration profile to minimize outdiffusion. A thinner, more highly doped active region is thereby achieved.

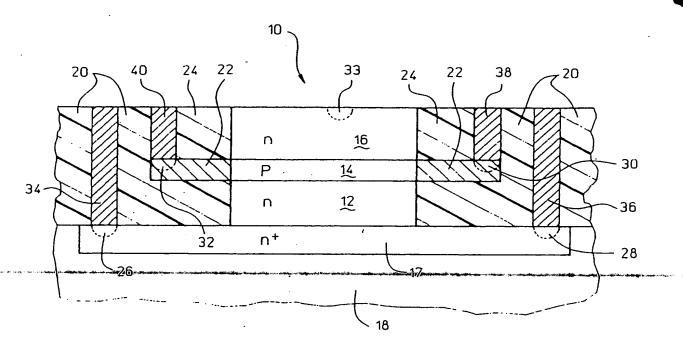


FIG 1



EUROPEAN SEARCH REPORT

Application Number

EP 92 31 1671

	DOCUMENTS CONSI	DERED TO BE RELEVANT	Γ	
Category	Citation of document with in of relevant pa	ndication, where appropriate, ssages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.CL5)
X	pages 2043 - 2064	ber 1989, NEW YORK US Heterojunction bipolar i-Ge alloys'	1-6	H01L21/331 H01L21/20 H01L29/161 H01L29/73
X	December 1988, SAN pages 562 - 565 P. NAROZNY ET AL. '	Si/SiGe heterojunction with graded gap SiGe lar beam epitaxy'	1-7	·
D,X	IEEE ELECTRON DEVICE LETTERS., vol.11, no.4, April 1990, NEW YORK US pages 171 - 17.3 GARY L. PATTON ET AL. '75-GHz ft SiGe-base heterojunction bipolar transistors' * the whole document *		1-6	TECHNICAL FIELDS SEARCHED (Int.Cl.5)
D,X	IEEE ELECTRON DEVICE LETTERS., vol.10, no.12, December 1989, NEW YORK US pages 534 - 536 GARY L. PATTON ET AL. 'Graded-SiGe-base, poly-emitter heterojunction bipolar transistors' * the whole document *		1-6	H01L
A	EP-A-O 459 122 (INT MACHINES CORPORATIO * the whole documen	N) t * 	1,4-7	
		-/		
	The present search report has b	cen drawn up for all claims		
Place of searth Date of completion of the search				Examiner
	THE HAGUE	31 May 1995	Vis	sentin, A
X : part Y : part doci A : tech O : non	CATEGORY OF CITED DOCUMER icularly relevant if taken alone icularly relevant if combined with and ument of the same category inblogical backgroundwritten disclosure rmediate document	F. : earlier patent doc after the filing da	ument, but pub- te the application r other reasons	ished on, or

EPO FORM 1503 03.82 (POCCOL)

EUROPEAN SEARCH REPORT

Application Number EP 92 31 1671

		DERED TO BE RELEVAN		AT ACCURATION OF THE	
Category	Citation of document with in of relevant pas		Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Cl.5)	
Α.	JOURNAL OF THE ELECTROCHEMICAL SOCIETY, vol.138, no.6, June 1991, MANCHESTER, NEW HAMPSHIRE US pages 1802 - 1806 S. ARONOWITZ ET AL. 'P-type dopant diffusion control in silicon using germanium'		1,4	againe from nedaciones in consequencia consequencia con consequencia formacione de la consequencia con conse	
D,A	IEEE ELECTRON DEVICE vol.10, no.11, Nover pages 503 - 505	LETTERS., mber 1989, NEW YORK US ET AL. 'Small-geometry, i-Sil-xGex	1,4,6		
Á	* the whole document IEEE ELECTRON DEVICE	t * . E LETTERS.,	1-4,6,7		
-	vol.12, no.2, February 1991, NEW YORK US pages 42 - 44 E.J. PRINZ ET AL. 'The effects of base dopant outdiffusion and undoped Sil-xGex junction spacer layers in Si/Sil-xGex/Si heterojunction bipolar transistors' * the whole document *			TECHNICAL FIELDS SEARCHED (Int.Cl.5)	
D,A	US-A-4 835 112 (JAMI	ES R. PFIESTER)			
				v,	
	The present search report has be	en drawn up for all claims			
Place of search Date of completion of the search				Examiner	
THE HAGUE		31 May 1995	Visentin, A		
CATEGORY OF CITED DOCUMENTS T: theory or E: earlier pa X: particularly relevant if taken alone Y: particularly relevant if combined with another document of the same category A: technological background			ciple underlying the invention document, but published on, or		